

Symbol	Typ	Titel
<b>H</b>	<b>Sektion</b>	<b>SECTION H — ELECTRICITY</b>
<b>H05</b>	<b>Klasse</b>	<b>ELECTRIC TECHNIQUES NOT OTHERWISE PROVIDED FOR</b>
<b>H05H</b>	<b>Unterklasse</b>	<b>PLASMA TECHNIQUE (ion-beam tubes H01J 27/00; magnetohydrodynamic generators H02K 44/08; producing X-rays involving plasma generation H05G 2/00); PRODUCTION OF ACCELERATED ELECTRICALLY- CHARGED PARTICLES OR OF NEUTRONS (obtaining neutrons from radioactive sources G21, e.g. G21B, G21C, G21G); PRODUCTION OR ACCELERATION OF NEUTRAL MOLECULAR OR ATOMIC BEAMS (atomic clocks G04F 5/14; devices using stimulated emission H01S; frequency regulation by comparison with a reference frequency determined by energy levels of molecules, atoms, or subatomic particles H03L 7/26)</b>
<b>H05H 1/00</b>	<b>Hauptgruppe</b>	<b>Generating plasma; Handling plasma (application of plasma technique in thermonuclear fusion reactors G21B 1/00)</b>
H05H 1/02	1-Punkt Untergruppe	. Arrangements for confining plasma by electric or magnetic fields; Arrangements for heating plasma (electron optics H01J)
H05H 1/03	2-Punkt Untergruppe	. . using electrostatic fields [3]
H05H 1/04	2-Punkt Untergruppe	. . using magnetic fields substantially generated by the discharge in the plasma
H05H 1/06	3-Punkt Untergruppe	. . . Longitudinal pinch devices
H05H 1/08	3-Punkt Untergruppe	. . . Theta pinch devices
H05H 1/10	2-Punkt Untergruppe	. . using applied magnetic fields only
H05H 1/11	3-Punkt Untergruppe	. . . using cusp configuration (H05H 1/14 takes precedence) [3]
H05H 1/12	3-Punkt Untergruppe	. . . wherein the containment vessel forms a closed loop, e.g. stellarator
H05H 1/14	3-Punkt Untergruppe	. . . wherein the containment vessel is straight and has magnetic mirrors
H05H 1/16	2-Punkt Untergruppe	. . using applied electric and magnetic fields
H05H 1/18	3-Punkt Untergruppe	. . . wherein the fields oscillate at a very high frequency, e.g. in the microwave range
H05H 1/20	2-Punkt Untergruppe	. . Ohmic heating
H05H 1/22	2-Punkt Untergruppe	. . for injection heating
H05H 1/24	1-Punkt Untergruppe	. Generating plasma [2]
H05H 1/26	2-Punkt Untergruppe	. . Plasma torches [2]
H05H 1/28	3-Punkt Untergruppe	. . . Cooling arrangements [3]
H05H 1/30	3-Punkt Untergruppe	. . . using applied electromagnetic fields, e.g. high-frequency or microwave energy (H05H 1/28 takes precedence) [3]
H05H 1/32	3-Punkt Untergruppe	. . . using an arc (H05H 1/28 takes precedence) [3]
H05H 1/34	4-Punkt Untergruppe	. . . . Details, e.g. electrodes, nozzles [3]
H05H 1/36	5-Punkt Untergruppe	. . . . . Circuit arrangements (H05H 1/38, H05H 1/40 take precedence) [3]
H05H 1/38	5-Punkt Untergruppe	. . . . . Guiding or centering of electrodes [3]
H05H 1/40	5-Punkt Untergruppe	. . . . . using applied magnetic fields, e.g. for focusing or rotating the arc [3]

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H05H 1/42	4-Punkt Untergruppe	. . . with provisions for introducing materials into the plasma, e.g. powder, liquid (electrostatic spraying, spraying apparatus with means for charging the spray electrically B05B 5/00) [3]
H05H 1/44	4-Punkt Untergruppe	. . . using more than one torch [3]
H05H 1/46	2-Punkt Untergruppe	. . using applied electromagnetic fields, e.g. high frequency or microwave energy (H05H 1/26 takes precedence) [3]
H05H 1/48	2-Punkt Untergruppe	. . using an arc (H05H 1/26 takes precedence) [3]
H05H 1/50	3-Punkt Untergruppe	. . . and using applied magnetic fields, e.g. for focusing or rotating the arc [3]
H05H 1/52	2-Punkt Untergruppe	. . using exploding wires or spark gaps (H05H 1/26 takes precedence; spark gaps in general H01T) [3]
H05H 1/54	1-Punkt Untergruppe	. Plasma accelerators [3]
<b>H05H 3/00</b>	<b>Hauptgruppe</b>	<b>Production or acceleration of neutral particle beams, e.g. molecular or atomic beams [3]</b>
H05H 3/02	1-Punkt Untergruppe	. Molecular or atomic-beam generation, e.g. resonant beam generation (gas masers H01S 1/06) [3]
H05H 3/04	1-Punkt Untergruppe	. Acceleration by electromagnetic wave pressure [3]
H05H 3/06	1-Punkt Untergruppe	. Generating neutron beams (targets for producing nuclear reactions H05H 6/00; neutron sources G21G 4/02) [5]
<b>H05H 5/00</b>	<b>Hauptgruppe</b>	<b>Direct voltage accelerators; Accelerators using single pulses (H05H 3/06 takes precedence) [5]</b>
H05H 5/02	1-Punkt Untergruppe	. Details (targets for producing nuclear reactions H05H 6/00) [3]
H05H 5/03	2-Punkt Untergruppe	. . Accelerating tubes (vessels or containers of electric discharge tubes with improved potential distribution over surface of vessel H01J 5/06; shields of X-ray tubes associated with vessels or containers H01J 35/16) [4]
H05H 5/04	1-Punkt Untergruppe	. energised by electrostatic generators, e.g. by van de Graaff generator [4]
H05H 5/06	1-Punkt Untergruppe	. Tandem accelerators; Multi-stage accelerators
H05H 5/08	1-Punkt Untergruppe	. Particle accelerators using step-up transformers, e.g. resonance transformers [4]
<b>H05H 6/00</b>	<b>Hauptgruppe</b>	<b>Targets for producing nuclear reactions (supports for targets or objects to be irradiated G21K 5/08) [3]</b>
<b>H05H 7/00</b>	<b>Hauptgruppe</b>	<b>Details of devices of the types covered by groups H05H 9/00-H05H 13/00 (targets for producing nuclear reactions H05H 6/00) [3]</b>
H05H 7/02	1-Punkt Untergruppe	. Circuits or systems for supplying or feeding radio-frequency energy (radio-frequency generators H03B)
H05H 7/04	1-Punkt Untergruppe	. Magnet systems; Energisation thereof
H05H 7/06	1-Punkt Untergruppe	. Two-beam arrangements; Multi-beam arrangements
H05H 7/08	1-Punkt Untergruppe	. Arrangements for injecting particles into orbits
H05H 7/10	1-Punkt Untergruppe	. Arrangements for ejecting particles from orbits
H05H 7/12	1-Punkt Untergruppe	. Arrangements for varying final energy of beam
H05H 7/14	1-Punkt Untergruppe	. Vacuum chambers (H05H 5/03 takes precedence) [4]
H05H 7/16	2-Punkt Untergruppe	. . of the waveguide type [4]
H05H 7/18	2-Punkt Untergruppe	. . Cavities; Resonators [4]
H05H 7/20	3-Punkt Untergruppe	. . . with superconductive walls [4]
H05H 7/22	1-Punkt Untergruppe	. Details of linear accelerators, e.g. drift tubes (H05H 7/02-H05H 7/20 take precedence) [4]

Symbol	Typ	Titel
<b>H05H 9/00</b>	<b>Hauptgruppe</b>	<b>Linear accelerators (H05H 11/00 takes precedence)</b>
H05H 9/02	1-Punkt Untergruppe	. Travelling-wave linear accelerators
H05H 9/04	1-Punkt Untergruppe	. Standing-wave linear accelerators
<b>H05H 11/00</b>	<b>Hauptgruppe</b>	<b>Magnetic induction accelerators, e.g. betatrons</b>
H05H 11/02	1-Punkt Untergruppe	. Air-cored betatrons
H05H 11/04	1-Punkt Untergruppe	. Biased betatrons
<b>H05H 13/00</b>	<b>Hauptgruppe</b>	<b>Magnetic resonance accelerators; Cyclotrons</b>
H05H 13/02	1-Punkt Untergruppe	. Synchrocyclotrons, i.e. frequency-modulated cyclotrons
H05H 13/04	1-Punkt Untergruppe	. Synchrotrons
H05H 13/06	1-Punkt Untergruppe	. Air-cored magnetic resonance accelerators
H05H 13/08	1-Punkt Untergruppe	. Alternating-gradient magnetic resonance accelerators
H05H 13/10	1-Punkt Untergruppe	. Accelerators comprising one or more linear accelerating sections and bending magnets or the like to return the charged particles in a trajectory parallel to the first accelerating section, e.g. microtrons [4]
<b>H05H 15/00</b>	<b>Hauptgruppe</b>	<b>Methods or devices for acceleration of charged particles not otherwise provided for [4]</b>